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	Application No.	Applicant(s)
Notice of Allowability	10/578,723	TOKOROZUKI ET AL.
	Examiner	Art Unit
	Sean P. Shechtman	2125
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. This communication is responsive to <u>5/10/06</u> .		
2. The allowed claim(s) is/are 1.		
3.		
 Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☑ Information Disclosure Statements (PTO/SB/08),	5. Notice of Informal II 6. Interview Summary Paper No./Mail Da 7. Examiner's Amend 8. Examiner's Statem 9. Other	/ (PTO-413), ate

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DETAILED ACTION

1. Claim 1 is presented for examination.

Allowable Subject Matter

2. Claim 1 is allowed.

The following is an examiner's statement of reasons for allowance:

While J.P. Pub. No. 10-275753 to Kobayashi, supplied by applicant, teaches data for determining abnormality of semiconductor manufacturing equipment is output from the semiconductor manufacturing equipment (Abstract).

And, U.S. Pat. No. 5,923,553 to Yi teaches a monitoring database is created from past information pertaining to abnormal process conditions, wherein the monitoring database is used as reference when checking a subsequent processing condition (whole document).

And, U.S. Pub. No. 2002/0055194 to Takanabe teaches statistical process control using a standard deviation of inspected data (Page 3, paragraph 47).

None of Kobayashi, Yi, or Takanabe, taken either alone or in obvious combination disclose a manufacturing method of a semiconductor integrated circuit device having all the claimed features of applicant's instant invention, specifically including: "acquiring a search key assigning the header of the apparatus log data; (b2) extracting past data coinciding with the apparatus log data in a content of the header assigned with the acquired search key from a past data memory; (b3) calculating a standard deviation from the extracted past data; and (b4) detecting based on the calculated standard deviation whether the abnormal data are present in the apparatus log data or not, wherein, of assignment of the header with the search key, an assignment of an apparatus name is grouped to enable to apply on a group base". Also, there is

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no motivation to combine Kobayashi, Yi, or Takanabe to meet these limitations. It is for these reasons that applicant's invention defines over the prior art of record.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

3. The prior art or art made of record and not relied upon is considered pertinent to applicant's disclosure.

The following patents or publications are cited to further show the state of the art with respect to statistical process control system and method of calculating a control limit based on a statistical deviation and, a process catalog for categorizing control charts such that the control charts are organized for assignment of the same performance based control limit calculated using statistics formed by data for control limit values of the control charts.

U.S. Pat. No. 6,947,801 to Lin et al (Abstract).

4. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sean P. Shechtman whose telephone number is (571) 272-3754. The examiner can normally be reached on 9:30am-6:00pm, M-F.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Leo P. Picard can be reached on (571) 272-3749. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

SPS

Sean P. Shechtman

October 13, 2007

LEO PICARD SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 2100

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